



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/465,492
Filing Date December 16, 1999
Inventor Segal et al.
Assignee Honeywell International Inc.
Group Art Unit 1742
Examiner Wilkins, III
Attorney's Docket No. 30-5004(4015)
Title: Sputtering Targets Formed From Cast Materials

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.


Citation of the referenced art is respectfully requested.

Respectfully submitted,

Dated: August 12, 2003

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

EV318283138

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|  | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY. DOCKET NO. 30-5004(4015) | | SERIAL NO. 09/465,492 | |
| | | LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | | | | |
| | | APPLICANT Vladimir Segal et al. | | | | FILING DATE December 16, 1999 | |
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| | AR | | Susumu Sawada, "On Advanced Sputtering Targets of Refractory Metals and Their Silicides for VLSI-Applications", 12 th International Plansee Seminar (1989) Topic 5: Ultrapure Refractory Metals, pp. 201-222. | | | | |
| | AS | | P. Ding et al., "Copper Barrier, Seed Layer, and Planarization Technologies", June 10-12, 1997 VMIC Conference, pp. 87-92. | | | | |
| | AT | | "Nickel, Cobalt and Their Alloys", pub. By ASM International, December 2000, pages 76, 230-234. | | | | |
| EXAMINER | | | | DATE CONSIDERED | | | |
| <p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p> | | | | | | | |